

# Korea-Switzerland Joint Seminar

## 1. Title of Seminar:

The First Korea-Switzerland Joint Symposium on Materials and Interfaces in MEMS Applications

## 2. Period and Place:

June 20 ~ June 23, 2000, Daejeon, Korea

## 3. Coordinators:

Korea		Switzerland	
Name (Position)	Affiliation	Name (Position)	Affiliation
Young-Ho Cho (Professor)	KAIST	Jan-Anders E. Månson (Professor)	EPFL

## 4. Participants:

Korea : 7 Persons

Switzerland : 7 Persons

## 5. Objective and Effectiveness:

### Objective

The Symposium is intended to promote interdisciplinary research discussion and technical information exchange between Korea and Switzerland.

### Effectiveness

The technical presentations, made by Korean and Swiss invited speakers, focus on the micromaterials and interface issues involved in the development and application of MEMS technology. Also addressed are the status of current R&D activity in Korea and Switzerland and the trend of the future. The summing-up discussion session provides good opportunities to get together for discussing potential applications, promising devices and enabling technologies for more innovative MEMS.

## 6. Program:

Date	Speaker	Affiliation	Topic for Presentation
June 21	Joong Won LEE	LG-ELITE	Applications of Ferroelectric Thin Films in MEMS Devices
	Hannes BLEULER	ISR-EPFL	3D microstructuring of glass using electrochemical discharge machining (ECDM)
	Sang Mo SHIN	Micro Solutions	Industrial Prospect of MEMS using Micromaterials
June 22	Raphael HOLZER	IMS-EPFL	EPFL Center of Microtechnology (CMI)
	Young-Ho CHO	KAIST	Micromaterials and Process for MEMS Bonding and Packaging
	Kyung Ku YOON	KIMM	Micro Fabrication Technologies using Laser Beam and MEMS applications
	Hyun Jung Shin	SAIT	Data Storage System using Atomic Force Microscopy and MEMS Technology
	Tae Seok Kim	ASE, KOREA	Assembly and Package Interaction Of MEMS Accelerometer Sensor in Automotive Application
	Sukhan LEE	SAIT	Polysilicon-Based Micro Sensors, Micro Actuators, and Intelligent Systems Research at SAIT
	David MENDELS	LTC-EPFL	Aging and Internal Stresses Issues in MEMS
Jong-Ern KIM	Siberhergner Korea	The Water Jet Guided Laser in wafer cutting	

	Yves LETERRIER	LTC-EPFL	Nanosized Gas-Barrier Coatings on Polymers
	Johann MICHLER	LMPH-EPFL	Assessment of Mechanical Properties of Thin Films: Residual Stress, Youngs Modulus, Fracture Strength, Adhesion, and Load Bearing Capacity
	Paul MURALT	LC-EPFL	Processing Issues for Integrating Ferroelectric Thin Films in MEMS